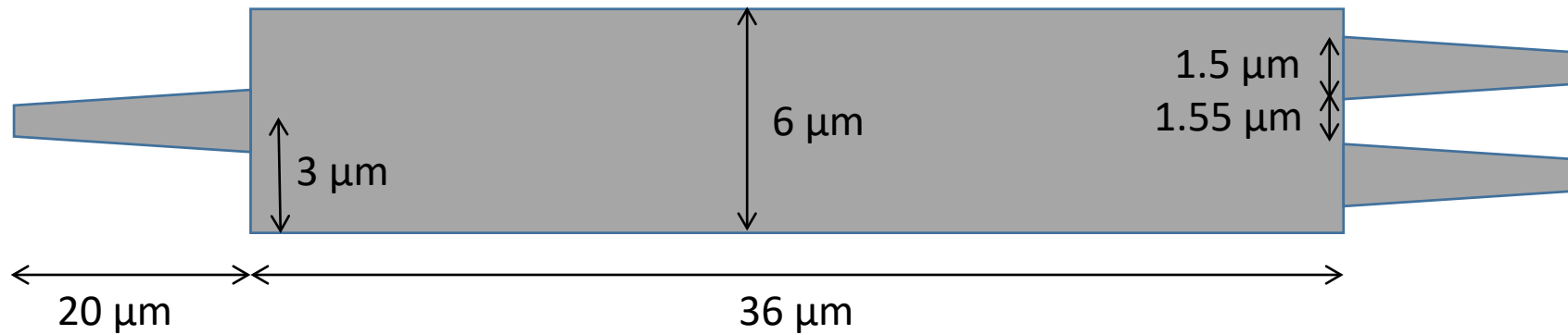
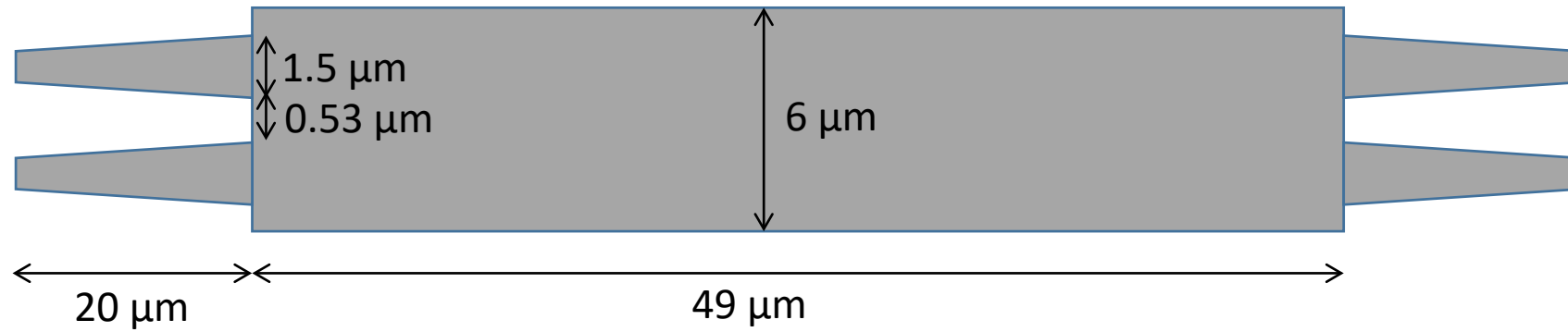




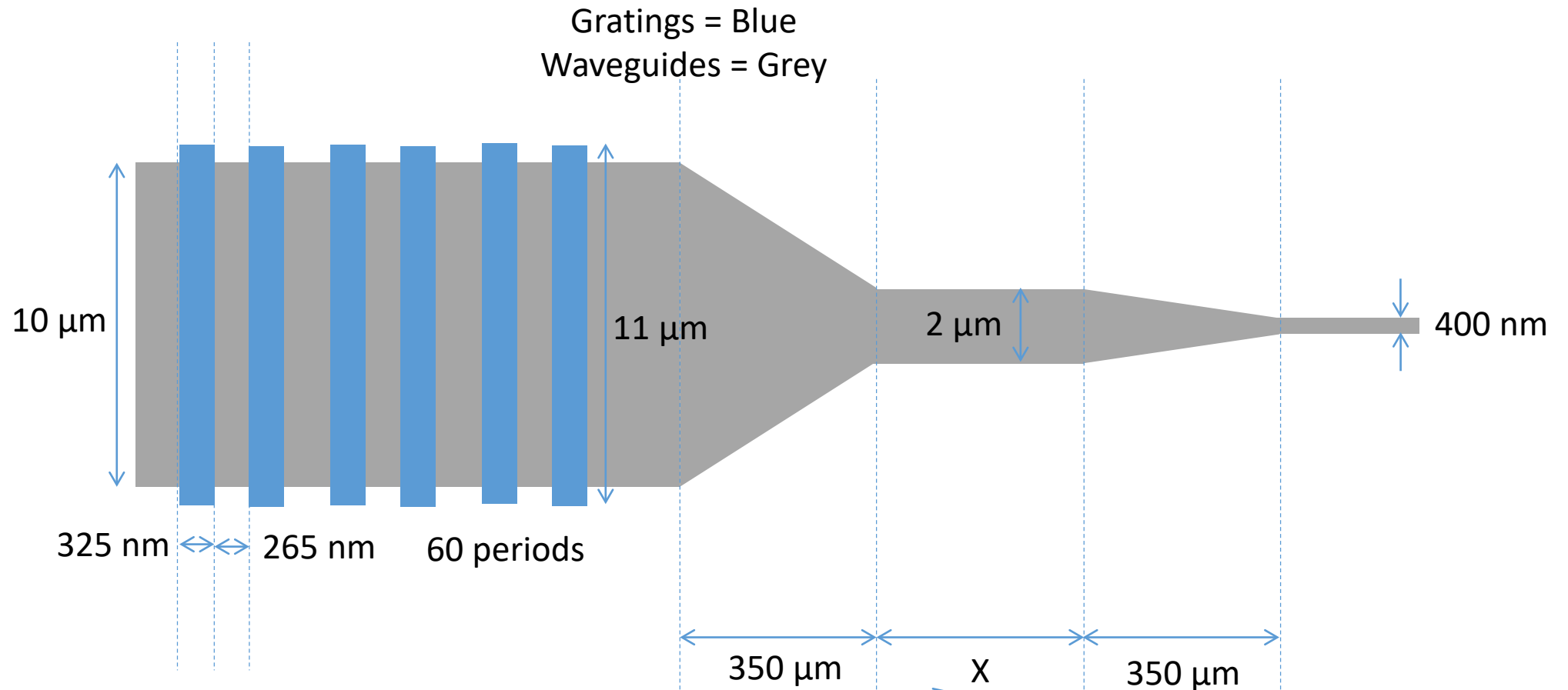
CORNERSTONE Device Dimensions for 340 nm SOI Platform $\lambda = 1550$ nm

Strip waveguide etch depth = 340 nm
Grating etch depth = 140 nm





Grating couplers (etch depth = 140 nm)



Use waveguide of width X for low loss routing to devices if required